

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Shimomura, et al.
Int'l Appl. No.	:	PCT/JP2004/015480
Int'l Filing Date	:	October 20, 2004
For	:	POLISHING PAD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD
Examiner	:	Unknown
Group Art Unit	:	Unknown

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to calculation of the number of claims, please amend the present application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.